



IFW

Docket No.: SON-1908/DIV
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Takeshi Nogami et al.

Application No.: 10/759,194

Confirmation No.: 7751

Filed: January 20, 2004

Art Unit: 2823

For: METHOD FOR PRODUCING
SEMICONDUCTOR DEVICE, POLISHING
APPARATUS, AND POLISHING METHOD

Examiner: F. L. Toledo

RESPONSE TO IDENTIFICATION OF DRAWING DEFICIENCIES

MS Issue Fee
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

INTRODUCTORY COMMENTS

In response to the Identification of Drawing Deficiencies dated April 27, 2007, please amend the above-identified U.S. patent application as follows:

Amendments to the Drawings begin on page 2 of this paper and include both an attached replacement sheet and an annotated sheet showing changes.

Remarks/Arguments begin on page 3 of this paper.

An **Appendix** including replacement drawing figures and a copy of the Identification of Drawing Deficiencies is attached following page 3 of this paper.